IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

APPLICANT: YANG, Tsun-Neng; GUNNG, Tai-Cheng; MA, Wei-Yang; YANG, Yu-Tang; TSAI, Ming-Ruesy; LAN, Kao-Chi

SERIAL NO.:

FILED: Herewith

TITLE: ION IMPLANTING APPARATUS

PRELIMINARY AMENDMENT

Commissioner for Patents
P. O. Box 1450
Alexandria, VA 22313-1450

Sir:

In conjunction with the filing of the present application, and prior to an initial Official Action on this matter, please amend the above-identified application as follows:

Preliminary Amendment: SPECIFICATION AMENDMENTS

In Paragraph [0010], please amend the paragraph as follows:

Other objectives and advantages of the present invention will become apparent upon reading the following descriptions and upon reference to the accompanying drawings ~~in which:~~.

In Paragraphs [0011], please amend the paragraph as follows:

FIG. 1 and FIG. 2 ~~show~~ are cross-sectional and perspective views showing a portion of an ion implanting apparatus according to the present invention~~; and~~.

In Paragraphs [0012], please amend the paragraph as follows:

FIG. 3 is a schematic view diagram of an ion implanting apparatus according to the present invention.

IN THE ABSTRACT

On page 15, please amend the Abstract as follows:

The ion implanting apparatus of the present invention ~~comprises~~ has a wafer cassette capable of loading a plurality of wafers, an implanting chamber including an implanting base, a cassette-

transferring module for moving the wafer cassette, and a wafer-transferring module for moving the wafer from the wafer cassette to the implanting base. The wafer cassette ~~comprises~~ has a plurality of irradiation tray for loading the wafer, while the implanting base ~~comprises~~ includes a guiding slot for guiding the irradiation tray. The cassette-transferring module ~~comprises~~ has a rack positioned on the wafer cassette, a gear for moving the wafer cassette by driving the rack through rotating, and a first stepping motor for driving the gear. The wafer-transferring module ~~comprises~~ includes a push plate for moving the irradiation tray from the wafer cassette to the implanting base, and a second stepping motor for driving the push plate.